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	Application Number		10695620	
	Filing Date		2003-10-27	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	First Named Inventor Alexa		xander Kadyshevitch	
(Not for submission under 37 CFR 1.99)	Art Unit		2881	t
(**************************************	Examiner Name	David A. Vanore		\ <u></u>
	Attorney Docket Numb	er	40006317-0045-552	

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Examiner Name	Davi	d A. Vanore	
Attorney Docket Numb	er	40006317-0045-552	

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Attorney Docket Number	er	40006317-0045-552		

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